

Abstract

A plain surface stage apparatus includes a platen having a plain surface, stationary type supports comprising at least three supporting members, and displacement type supports, each of which supports the platen and forms a displacement type supporting point at a position other than those of supporting points formed by the stationary type supports, wherein the displacement type supports expand and contract in a direction perpendicular to the plain surface of the platen so as to be displaced, and holds a selected displaced state of the displacement type supports.